

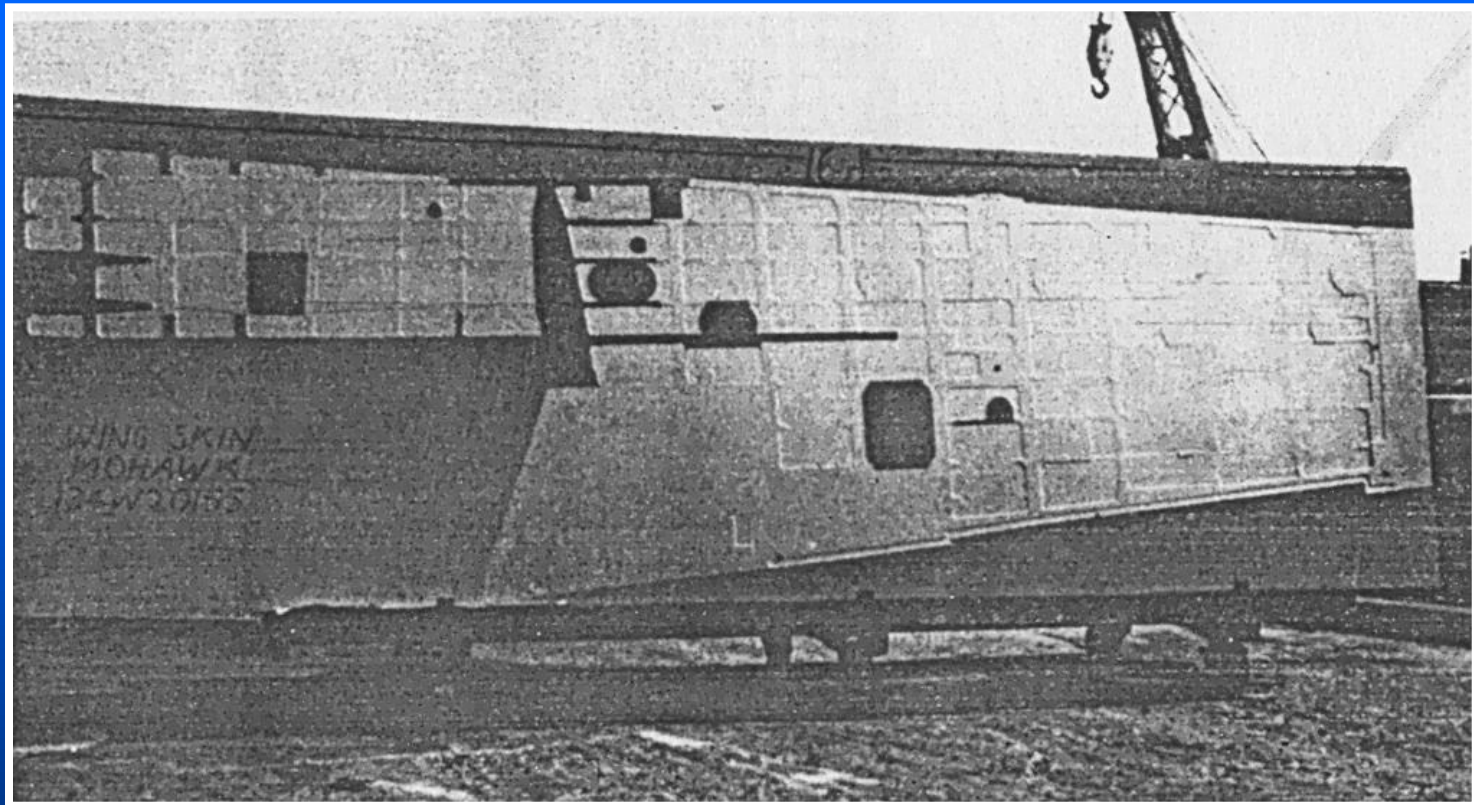
Chemical Machining

presented by

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Case Study 1

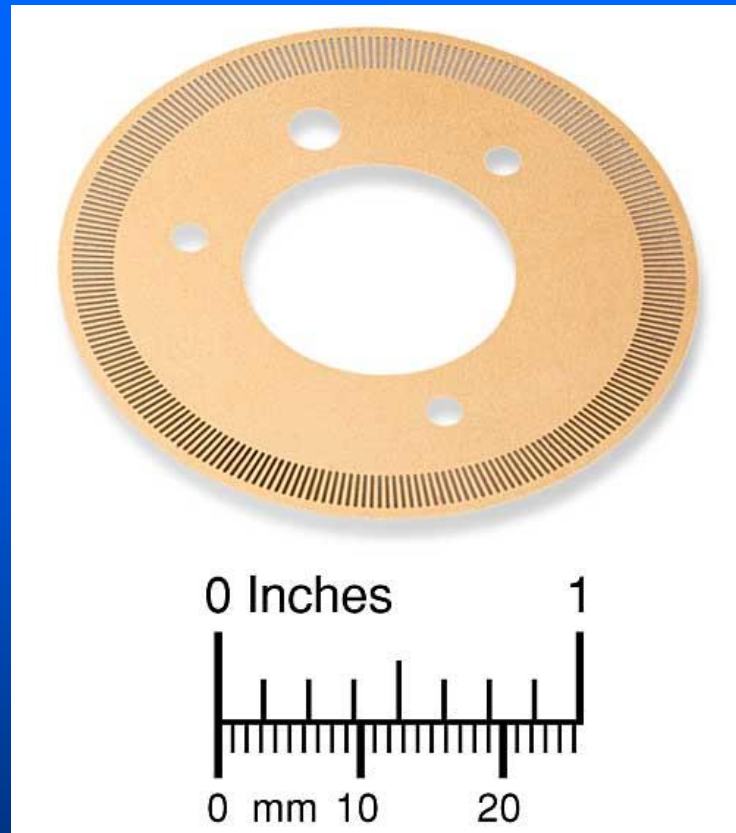


Skin of aluminum wing of an aircraft

(For better strength/weight ratio → remove unnecessary metal from numerous surface pockets)

(source Chemcut Corporation)

Case Study 2



Beryllium-copper alloy encoder disc

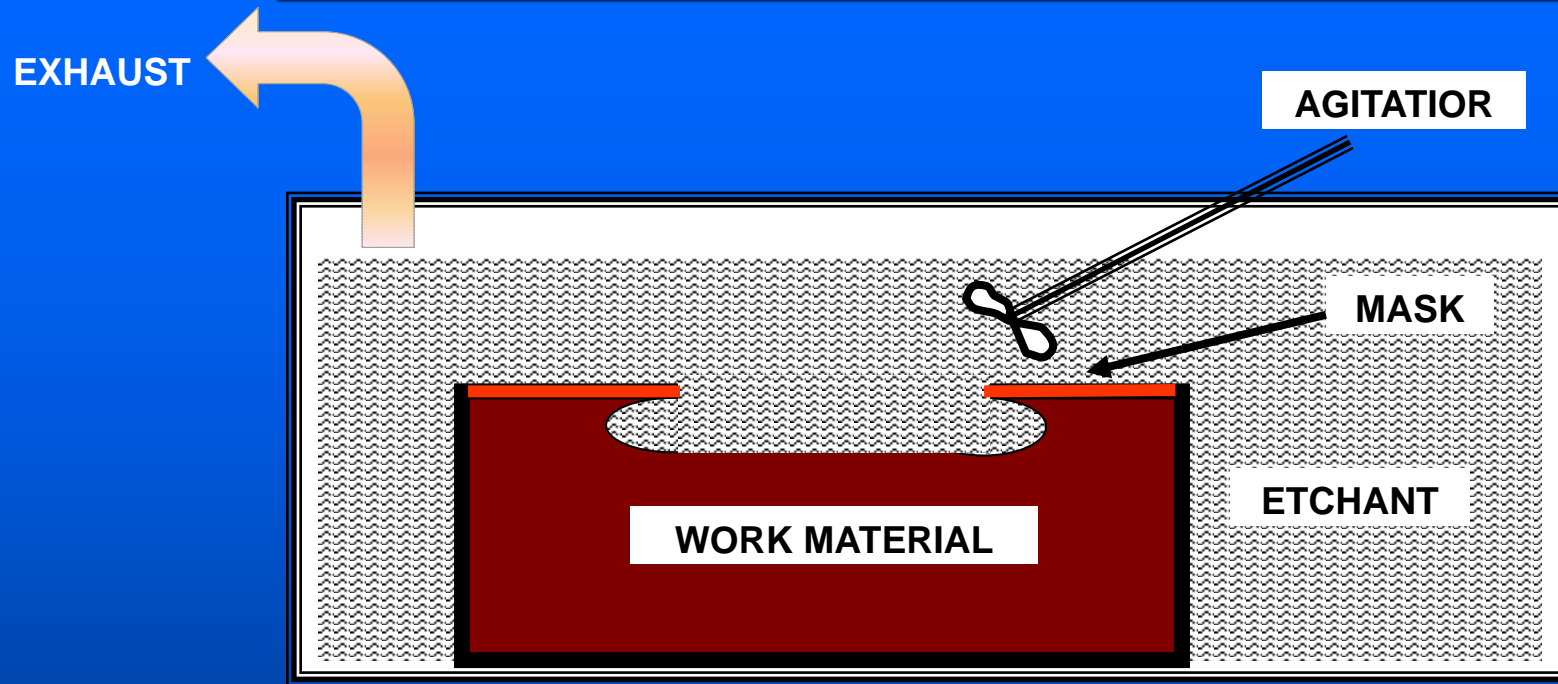
(Disc is 25 micron thick, Total 200 slits regularly spaced on disc at 1.8° separation)

Solution for both the cases

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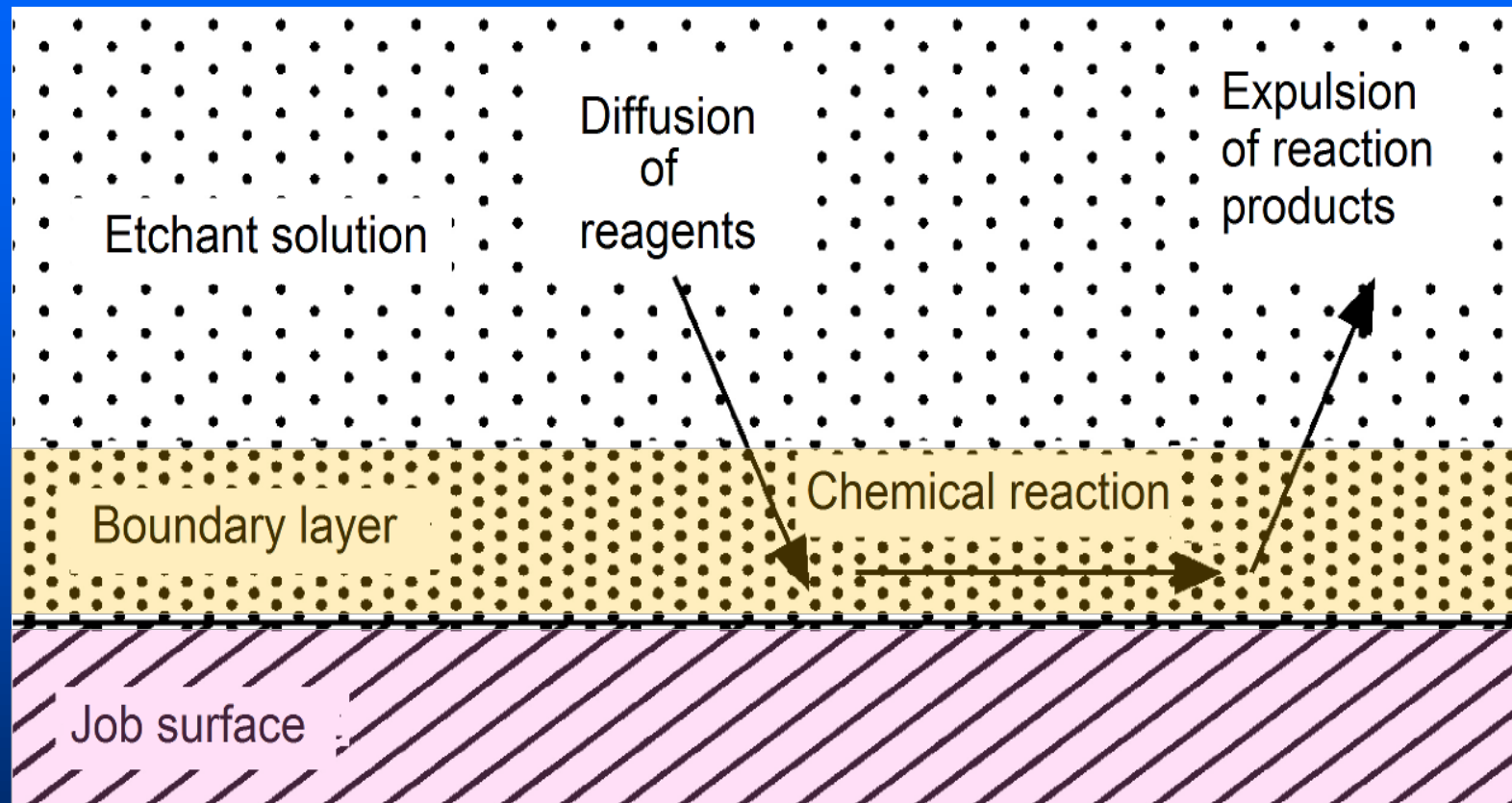
**..... Chemical Machining
(CHM)**

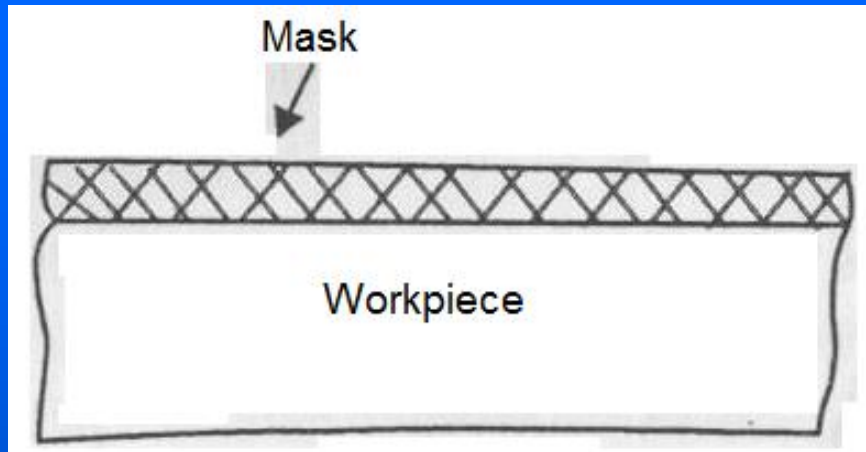
Basic Scheme of Chemical Machining



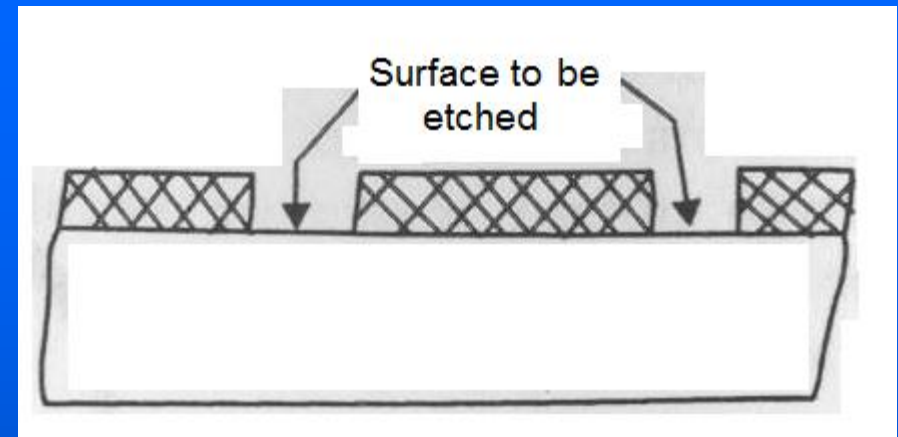
Requirements

- Mask
- Work piece or substrate
- Etchant (acid or alkali)
- Agitation
- Fume extraction (for reaction products)

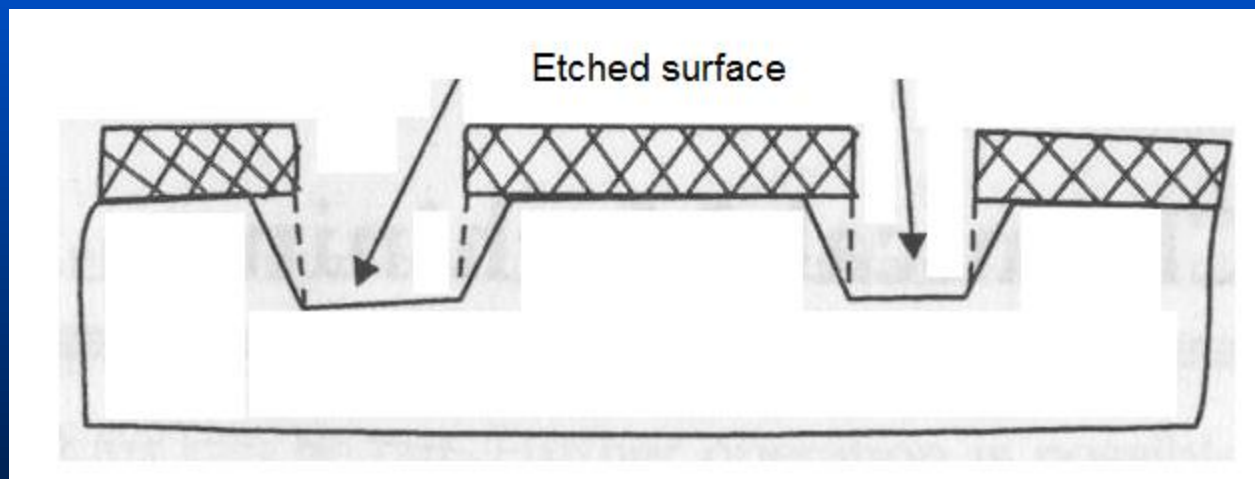




Maskant coating



Development of etching surface



Finished part

CHM Classification



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graph TD; A[CHM Classification] --> B[Chemical Milling]; A --> C[Chemical Blanking]; A --> D[Chemical Engraving]; A --> E[Photochemical Machining];
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The diagram is a flowchart titled 'CHM Classification'. It starts with a central title 'CHM Classification' at the top. From this title, four arrows point downwards to four separate boxes. The first box on the left is 'Chemical Milling' and contains two bullet points: 'weight reduction' and 'blind detailing'. The second box on the right is 'Chemical Blanking' and contains one bullet point: 'through detailing'. The third box on the bottom left is 'Chemical Engraving' and contains one bullet point: 'detailing upto very limited depth'. The fourth box on the bottom right is 'Photochemical Machining' and is empty. The boxes are arranged in a 2x2 grid, with 'Chemical Milling' and 'Chemical Blanking' in the top row, and 'Chemical Engraving' and 'Photochemical Machining' in the bottom row.

Chemical Milling

- weight reduction
- blind detailing

Chemical Blanking

- through detailing

Chemical Engraving

- detailing upto very limited depth

Photochemical Machining

Classification of masks

Cut & Peel type



1. Vinyl, Neoprene rubber, Bee wax
2. Applied by flow, dip or spray
3. Mask thickness: 0.03-0.13 mm
4. Unnecessary portion cut & peeled

- mask material is first applied on the entire surface of the substrate,
- the mask is cut along a template with a sharp cutter,
- Unwanted portion of mask is peeled off to expose the area to be milled.

Classification of masks

Screen print



1. Silk or stainless steel mesh which has a stencil placed upon the material to be machined

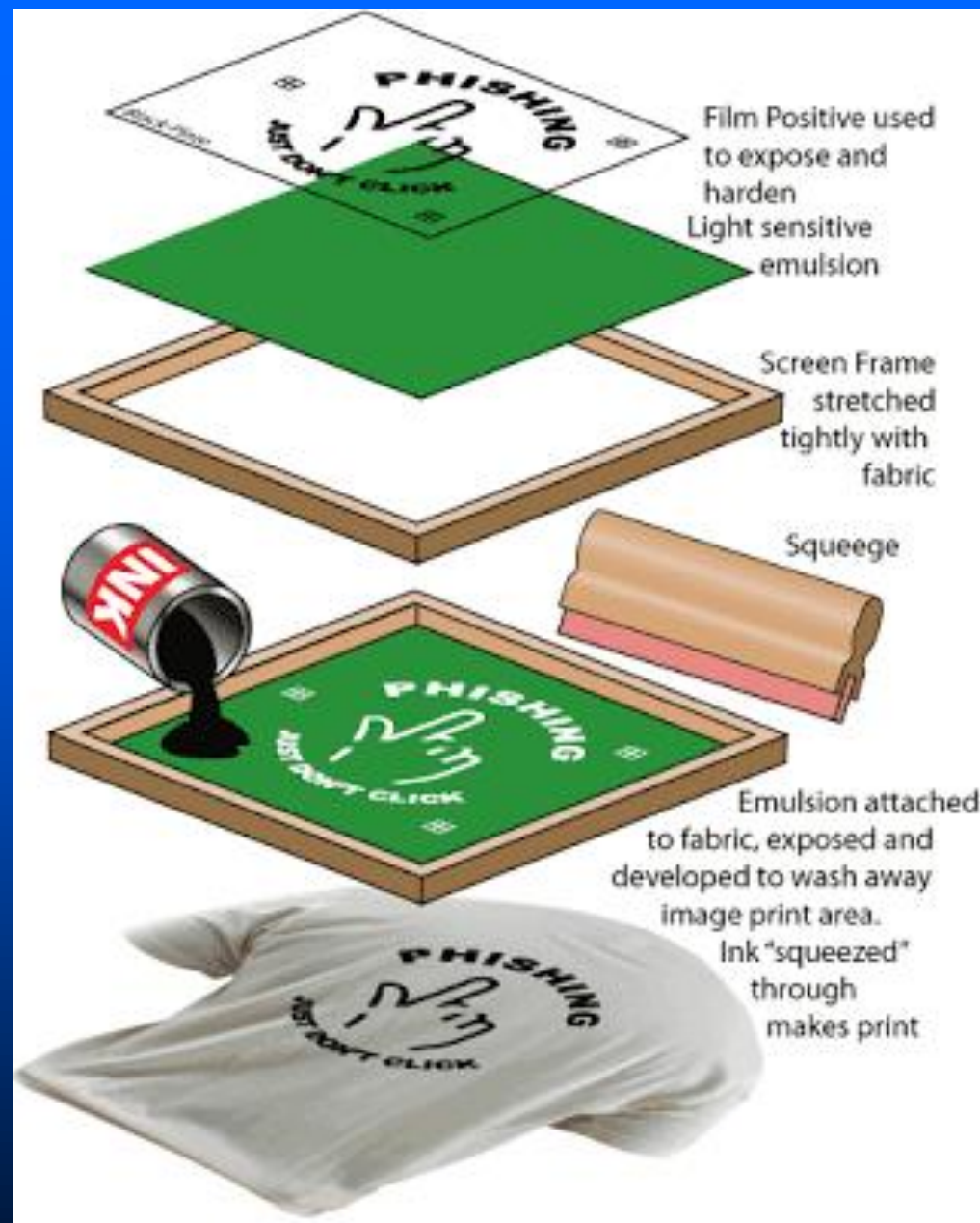
- ❑ Uses screens (mesh) made of silk, synthetic fiber such as nylon and polyester, or fine filament of stainless steel.
- ❑ Negative images of the needed patterns are created on the screen, → then resistive ink is applied by press-roller onto the substrate through the screen to create the final patterns.

Screen print

Photo-resist is a light-sensitive emulsion that is used as a masking material.

When exposed to light, it chemically transforms, hardens and adheres to the substrate.

Upon developing unexposed portion can be removed from the work surface, exposing the desired surface on job.



Classification of masks

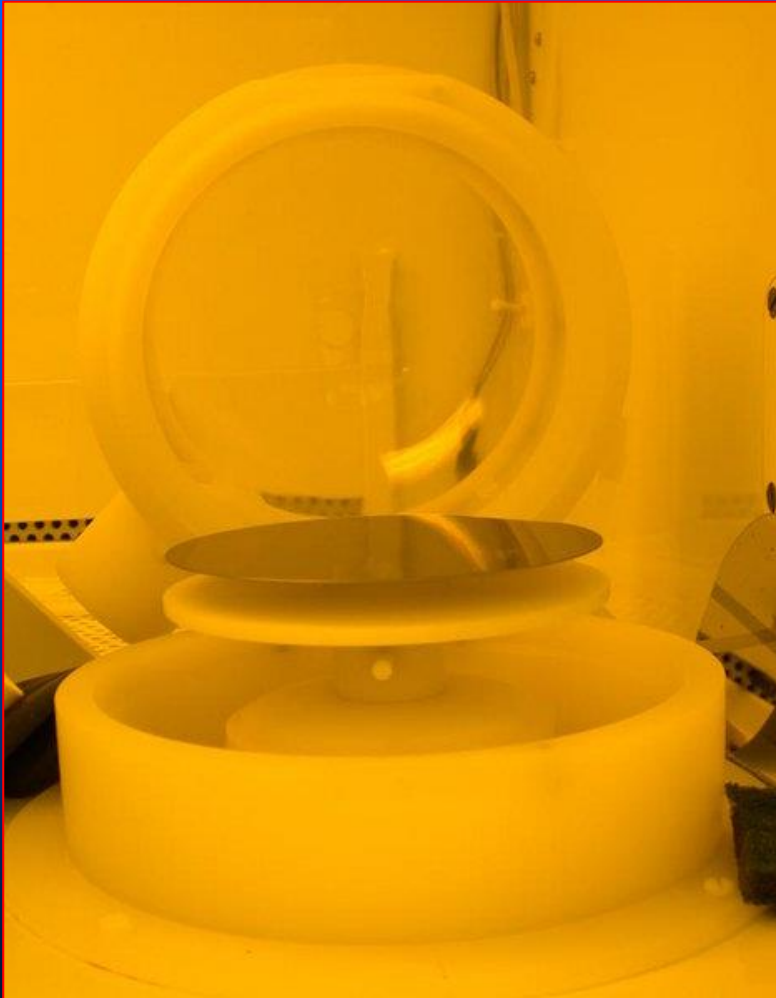
**Photo
resist**



1. Naturally occurring and synthetic photosensitive resins
2. Applied by spin coater and photographic projection technique. → so high production rate
3. Mask thickness: extremely thin (few microns). Not used for parts more than 1.25mm thick and 1.5 m long
4. Can handle highly corrosive etchants

□ The photo resist method creates very fine and accurate but thin resist patterns that provide small chemical resistances to strong alkali and acidic etchants. ← It is mostly used only for small depth applications.

Applying photo resist by Spin Coater



Rotation (@ around 5000 rpm) is continued while the fluid spins off the edges of the substrate, until the desired thickness of the film is achieved.

The applied solvent is usually volatile, and simultaneously evaporates.

The thickness of the film also depends on the concentration of the solution and the solvent.

Selection criteria for masks

Chemical Resistance	→ Deeper etching is possible with thicker mask
Part Configuration	→ Some masks are only applicable to flat parts
Quantity of parts	→ Masking process should be less labour intensive for high quantity parts
Cost	Cost affordability
Ease of removal	→ Delicate parts require easy removal of mask
Required resolution	→ Thicker masks result in less resolution

Uses of different masks

Cut & Peel type

1. Big structural parts
2. **Milling of aircraft components**
3. Missiles
4. **Space components**

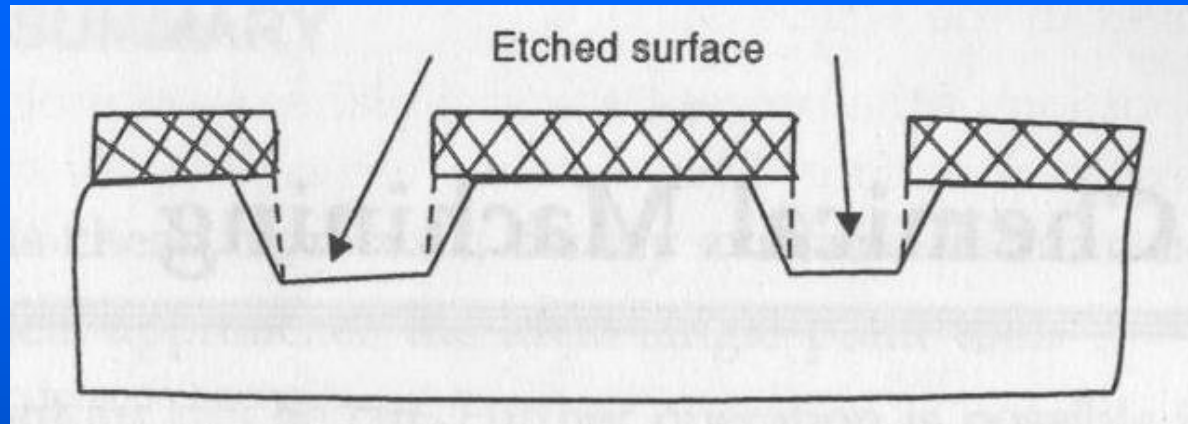
Photo resist

1. Small and thin components
2. **Never used for big components**
3. PCB
4. **Watch components like gears, small spiral rings**
5. Flat sheet metal components

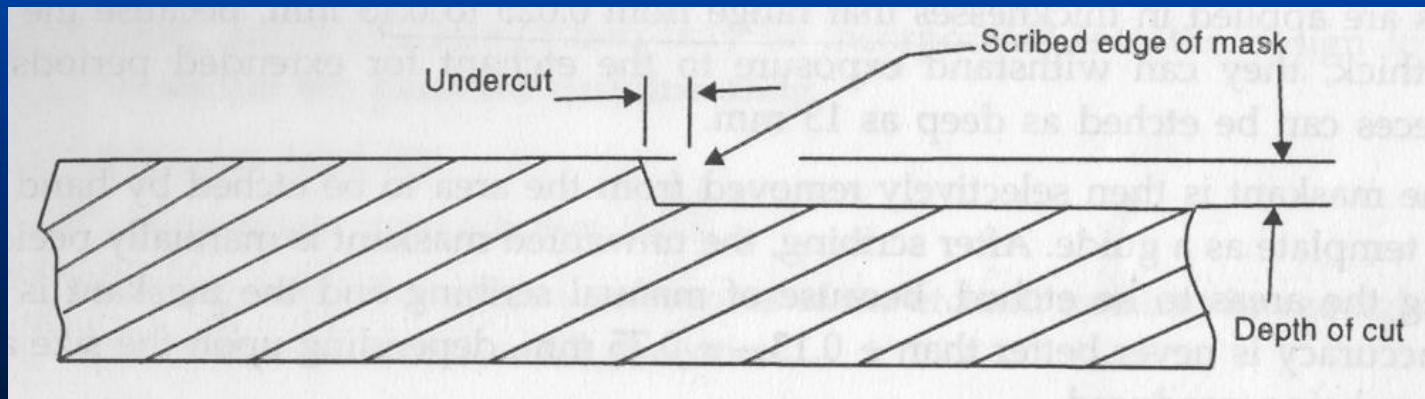
Screen print

1. Used for mass production
2. **But less accurate as compared to photo resist technique**

Undercut and Etch factor



$$\text{EtchFactor} = \frac{\text{Undercut}}{\text{Depth of etch}}$$



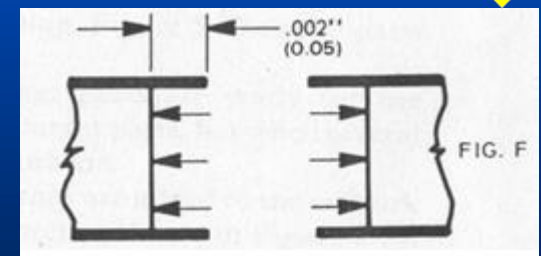
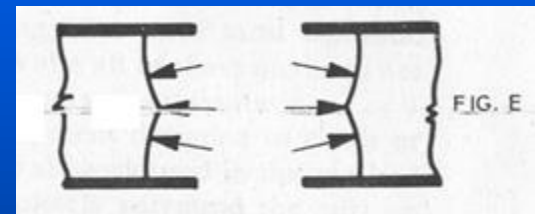
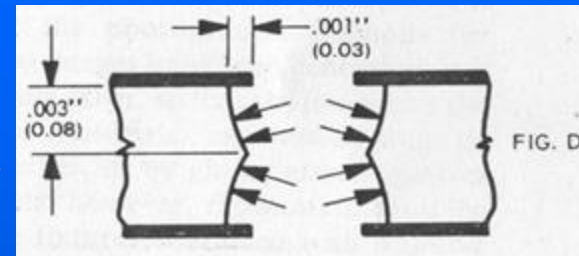
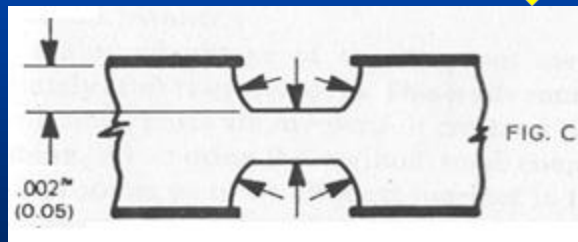
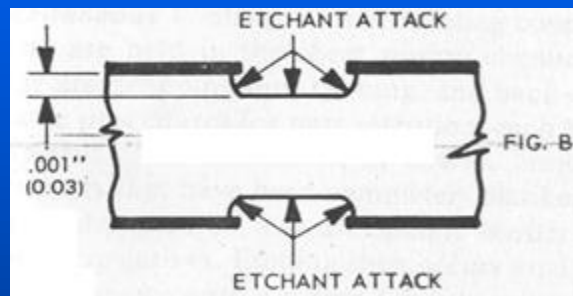
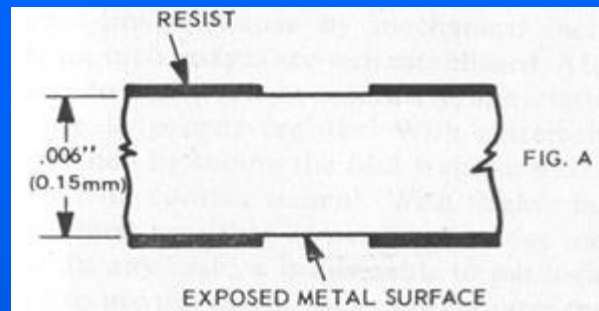
Etchant Applications and Their Characteristics

Metal	Preferred etchant	Etch rate (mm/min)	Etch factor
Aluminum	FeCl_3	0.025	1.7:1
Copper	FeCl_3	0.050	2.7:1
Nickel alloys	FeCl_3	0.018	2.0:1
Phosphor-bronze	Chromic acid	0.013	2.0:1
Silver	FeNO_3	0.020	1.5:1
Titanium	HF	0.025	2.0:1
Tool steel	HNO_3	0.018	1.5:1

Etchant selection

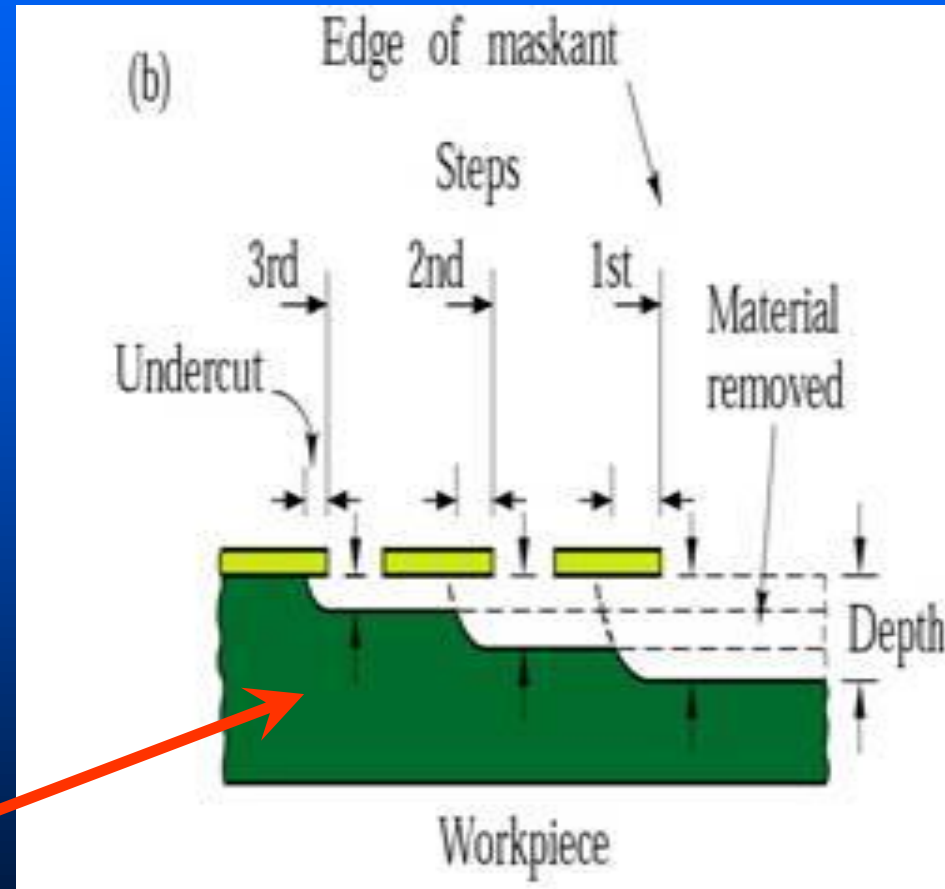
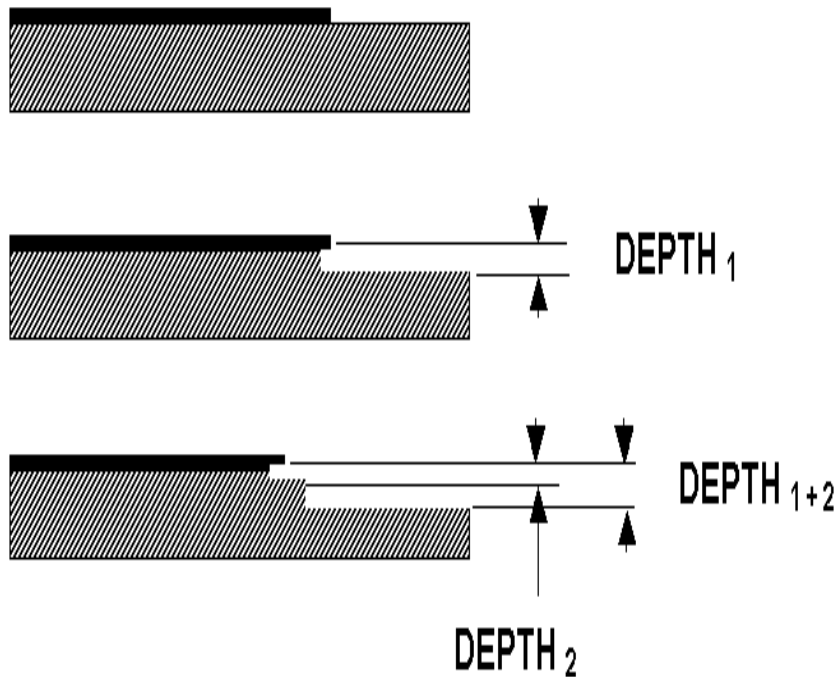
Required surface finish →	Some combinations of material and etchant result in the formation of surface oxides, which degrades the finish
Removal rate →	Faster rate lowers the cost, but attacks the resist bond, results in poor finish, or produces high heat
Material type →	Etchant must attack the material without causing <i>intra granular attack</i> or stress corrosion cracking
Etch depth →	Some etchants produce surface finishes that worsen with increasing depth
Type of resist →	Etchant must not destroy resist during the process time
Cost →	Cost of the etchant, maintenance, and disposal

Under cut in partially etched and fully etched parts



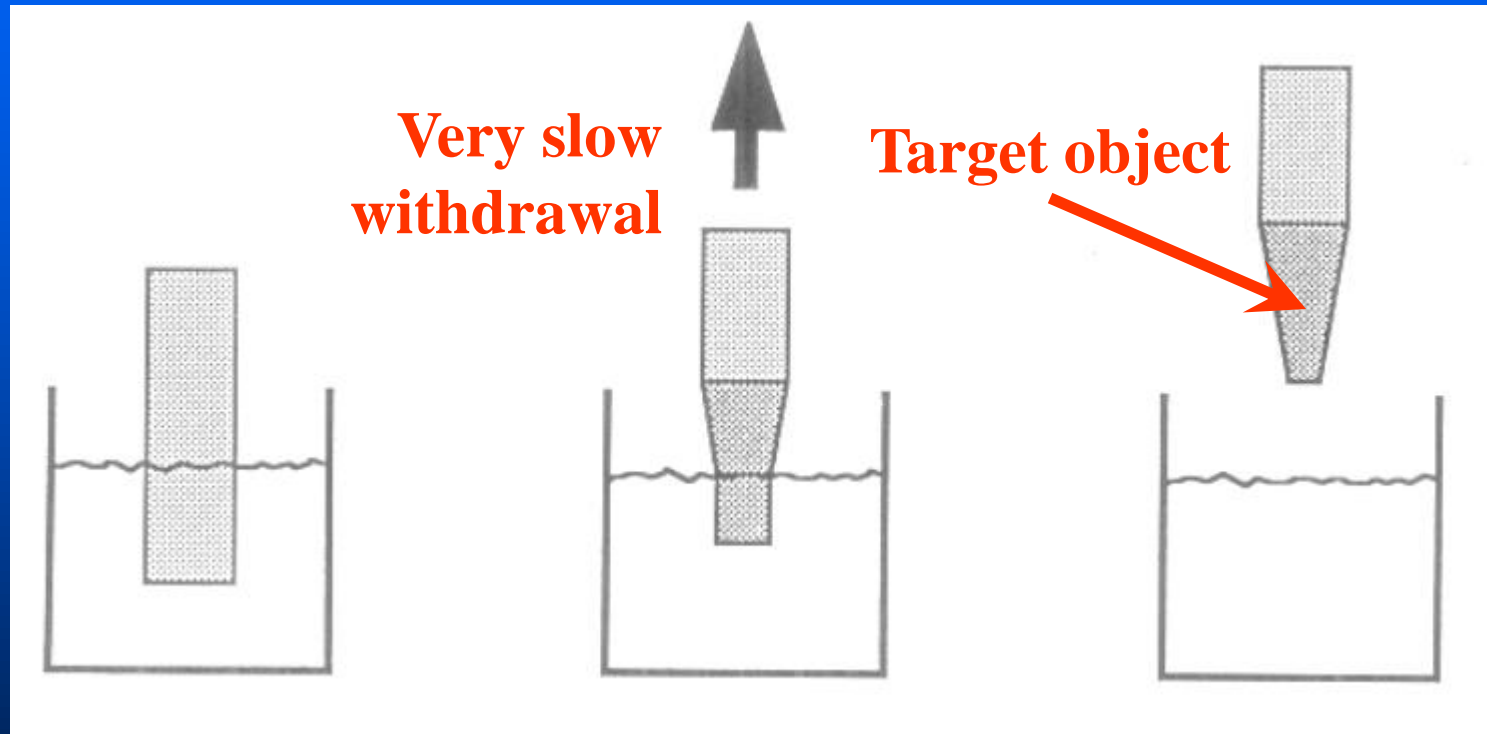
- Advantage of **double-sided etching**.
- Sidewise straightness (zero taper) can be achieved eventually

Process Sequence in Stepped Etching



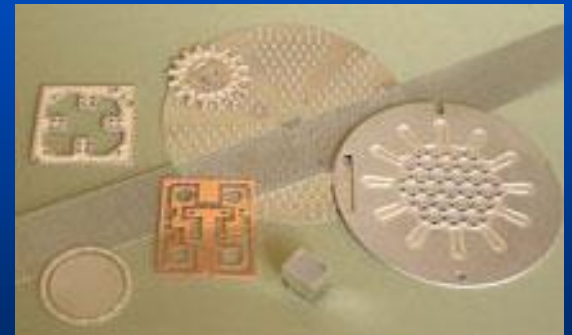
Target object

Taper achieved in CHM through controlled volume withdrawal



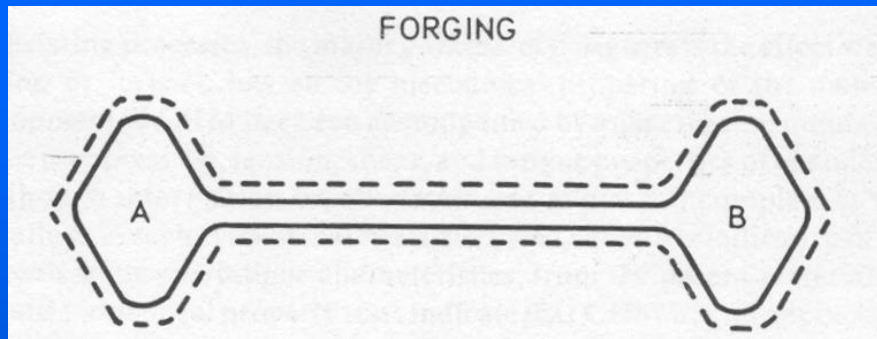
Advantages of CHM

- No conventional tools & dies (as required in stamping process)
- Dimensional repeatability
- Design flexibility (from prototype to mass production)
- Low cost
- Metal properties remain unchanged
- Burr free, crack & stress free parts
- Well-suited for too complex, too thin as well as too small parts

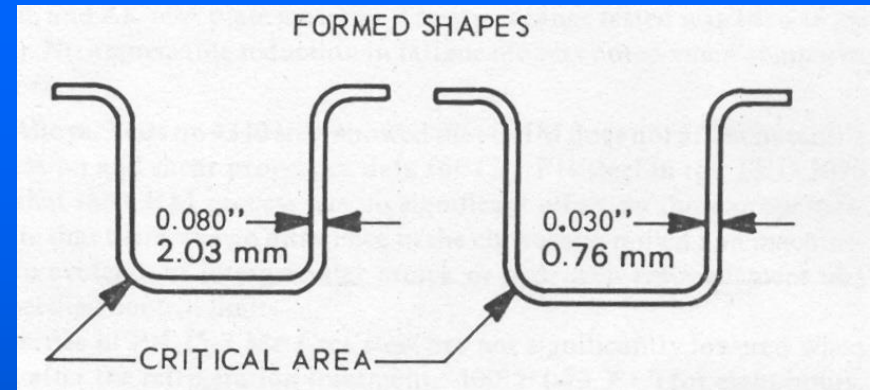


Applications of Chemical Machining

Finishing applications on forged/ formed/ machined parts



Heavier ends A & B can be formed to desired thickness by forging, the thin central portion cannot



Properly formed hat section



This part was first machined oversize to provide vertical webs, then reduced overall by CHM to provide web sections thinner than conventional methods